

**Amendments to the Claims:**

This listing of claims will replace all prior versions, and listings, of claims in the application:

**Listing of Claims:**

1. (currently amended) A fabrication method, comprising the steps of:  
  
monitoring the exhaust of a process chamber; and  
  
automatically sampling said exhaust when a ~~predetermined event~~ particle excursion occurs.
2. (original) The method of Claim 1, wherein said step of monitoring is done using an in-situ particle monitor.
3. (original) The method of Claim 1, wherein said step of sampling is done by inserting a collection device into said exhaust.
4. (canceled)
5. (original) The method of Claim 1, wherein said exhaust is sampled by redirecting said exhaust to a sampling area.
6. (original) The method of Claim 1, wherein an electrical control signal of said process chamber is monitored and correlated to said event.
7. (currently amended) A fabrication method, comprising the steps of:  
  
monitoring at least one signal of a process chamber; and  
  
sampling the exhaust from said process chamber when a ~~predetermined event occurs~~ detecting a given particle flux by an in-situ particle monitor located in said exhaust.
8. (original) The method of Claim 7, wherein said signal is an electrical control signal.
9. (currently) The method of Claim 7, wherein ~~said predetermined event is the deleting occurs at~~ a variation in said signal.
- 10-13. (canceled)

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14. (currently amended) A wafer processing system, comprising:
  - a chamber with an exhaust;
  - a particle monitor located in said exhaust;
  - wherein said particle monitor is connected to cause a particle sampler to gather samples from said exhaust when a predetermined particle flux is detected.
15. (original) The system of Claim 14, wherein said sampler gathers samples by being inserted into said exhaust.
16. (original) The system of Claim 14, wherein said sampler gathers samples by opening valves so that said exhaust passes to a sampling area.
17. (original) The system of Claim 14, wherein said sampler is a membrane filter.
18. (canceled)

TI-25047 - 3